

REMARKS

The Examiner has refused to consider non-English references that were cited in Applicant's IDS. MPEP § 609 III A(3) states that "(s)ubmission of an English language abstract of a reference may fulfill the requirement of a concise explanation" in regard to the relevance of each reference. Where the information listed is not in the English language, but was cited in a search report or other action by a foreign patent office in a counterpart foreign application, the requirement for a concise explanation of relevance can be satisfied by submitting an English-language version of the search report or action which indicates the degree of relevance found by the foreign office."

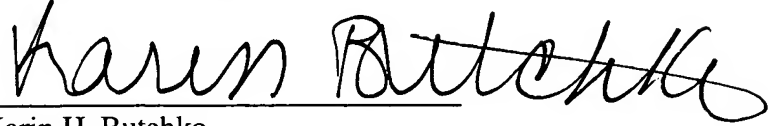
Applicant has filed herewith a foreign search report of a counterpart foreign application, which was also cited in the previously filed Information Disclosure Statement. Therefore, reconsideration of the previously-submitted IDS is requested. However, Applicant has resubmitted the references in the previously filed Information Disclosure Statement with English Abstracts with this response.

Claims 1-6 are rejected under 35 U.S.C. 102(e) as being anticipated by Engdahl et al (2001/0039168). Engdahl does not disclose a wafer rotating device that supports and rotates a wafer by a frictional force proportional to a contact load between cylindrical surfaces of rollers and a circumferential surface of the wafer as claimed. Engdahl discloses a wafer rotating device. A head assembly 52 retains a wafer against a water receiving plate 54 within a boundary defined by a retaining ring 56 that surrounds a plane of the wafer receiving plate 54. Fluid conduits 58 are distributed around the water receiving plate 54 to assist the head assembly 52 in retaining the wafer through either surface tension or a partial vacuum created between the wafer and the receiving plate 54 (paragraph 53 of the specification). The head assembly 52 does not support and rotate a wafer by a frictional force proportional to a contact load between cylindrical surfaces of rollers and a circumferential surface of the wafer as claimed. The claimed invention is not anticipated, and Applicant respectfully requests that the rejection be withdrawn.

Thus, claims 1-8 are in condition for allowance. No additional fees are seen to be required. If any additional fees are due, however, the Commissioner is authorized to charge Deposit Account No. 50-1482, in the name of Carlson, Gaskey & Olds, P.C., for any additional fees or credit the account for any overpayment. Therefore, favorable reconsideration and allowance of this application is respectfully requested.

Respectfully Submitted,

CARLSON, GASKEY & OLDS, P.C.

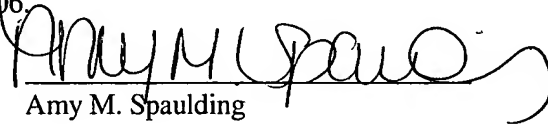


Karin H. Butchko
Registration No. 45,864
400 West Maple Road, Suite 350
Birmingham, Michigan 48009
Telephone: (248) 988-8360
Facsimile: (248) 988-8363

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CERTIFICATE OF MAIL

I hereby certify that the enclosed response is being deposited with the United States Postal Service as First Class Mail, postage prepaid, in an envelope addressed to Commissioner for Patents, P.O. Box 1450, Alexandria, VA 22313-1450, on March 16, 2006.


Amy M. Spaulding